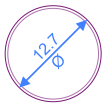
NOTES:

1. CUSTOMER WILL BE NOTIFIED OF ANY SUBSTANTIAL CHANGES IN DESIGN, PROCESS, OR MATERIALS.
2. TELAZTEC WILL KEEP RECORDS THAT TRACE SUBSTRATE MATERIAL, FAB, AND LOT.
3. **TELAZTEC WILL RETAIN MATERIAL MANUFACTURER GRADE CERTIFICATE WITH TRACEABLE MATERIAL LOT/MELT #.**
4. **TELAZTEC WILL PROVIDE A FIRST ARTICLE INSPECTION REPORT WITH FABRICATOR INTERFEROGRAMS, RADIUS, & DIMENSIONAL MEASUREMENTS.**
5. **ALL OPTICAL SPECIFICATIONS NOT LISTED BELOW PER MIL-PRF-13830B.**
6. PARTS ARE **RoHS / REACH** COMPLIANT. **RoHS / REACH CERTIFICATES** TO BE INCLUDED IN FAI REPORT.
7. **OPTICS PACKAGED IN NON-CONTACT, NON-PARTICULATING, ULTRA-LOW-OUTGASSING PETG CONTAINERS.**
8. **AR TREATMENT: RAR-S, RAR-S1, RAR-M, RAR-L, RAR-L1, RAR-L2** or **RAR-VL** Both S1 & S2

RANDOM ANTI-REFLECTIVE (RAR) SURFACE RELIEF NANO-TEXTURE ETCHED INTO THE OPTIC SURFACES. PROVIDES GRADED INDEX FUNCTION WITH NO ADDED ABSORPTION.
SPECIFY SPECTRAL BAND SHORT WAVE (S) THRU VERY LONG WAVE (VL).

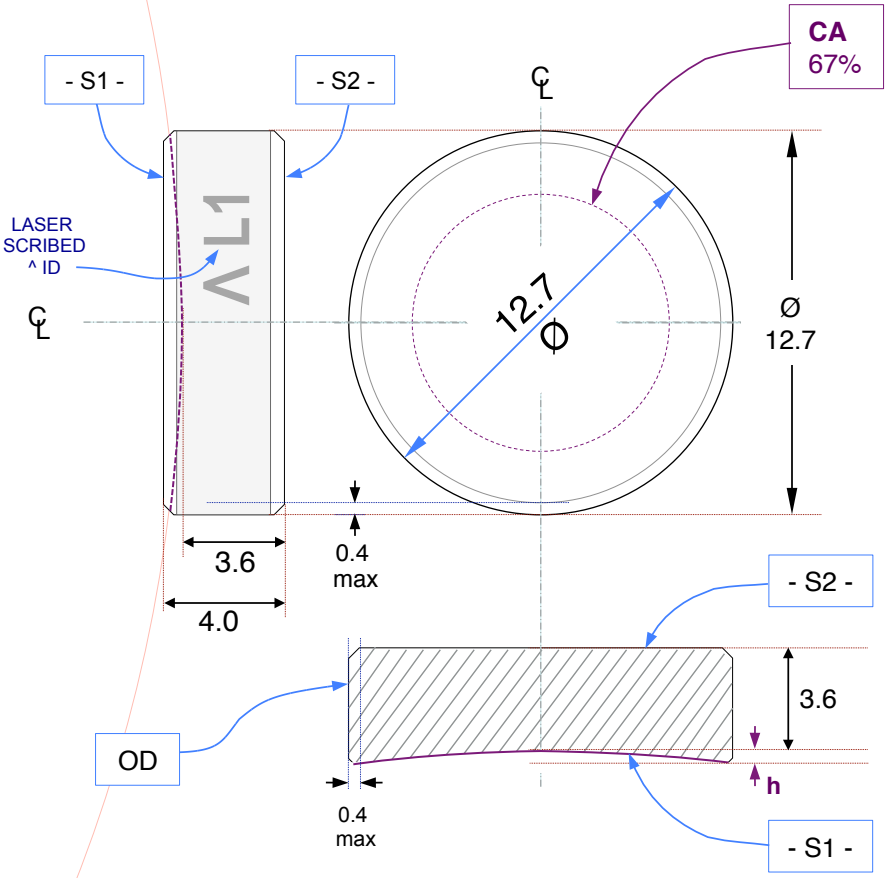
SINGLE SURFACE REFLECTION, AOI=0°
'S' – R<0.05% 250-360nm and R<0.3% 450-550nm
'S1' – R<0.1% 300-400nm and R<0.05% 450-550nm
'M' – R<0.1% 350-700nm, R<0.05% at 780nm, and R<0.2% 950-1100nm
'L' – R<0.1% 500-800nm and R<0.3% 900-1100nm
'L1' – R<0.05% 510-540nm, R<0.1% 1030-1085nm
'L2' – R<0.1% 550-800nm, R<0.05% at 1064nm, and R<0.3% 1250-1500nm
'VL' – R<0.1% 600-900nm, R<0.05% 1050-1300nm, and R<0.3% 1400-1600nm

RAR Nano-Texture Laser Induced Damage Threshold (LiDT):
ISO 21254 Pulsed LiDT @ 355nm, 6ns, >30 J/cm² (3X any thin film AR coating)
ISO 11254 Pulsed LiDT @ 532nm, 10ns, >40 J/cm²
ISO 11254 Pulsed LiDT @ 1064nm, 10ns, >60 J/cm² (3X any thin film AR coating)
CW LiDT @ 1070nm, >15 MW/cm² (PSEOC scanning protocol, 8-10X any coating)



OPTICAL MATERIAL:	High Purity Fused Silica, **CERTIFIED**
1/ 1x0,1 (0) **2/** 5;5 (A)	Corning 7980 **GRADE 0A**
SURFACES:	S1 CONCAVE. S2 PLANO.
RADIUS:	S1 -**50.85**mm S2 ∞
3/ 5() **; POWER:**	S1 +/- 0.5% S2 -
4/ CENTERING:	< **2** ARC MINUTES
CLEAR APERTURE, CA:	Ø **8.5**mm, centered (**67**%)
3/ () **SURFACE IRREGULARITY:**	S1 λ/10 IRR (PWR Removed) (0.2 fringe)
SURFACE FLATNESS:	S2 λ/10 P-V (0.2 fringe) at 633 nm over CA
5/ SURFACE QUALITY:	**10-5** SCRATCH-DIG
DIAMETER, Ø:	**12.7**mm +0.0 / **−0.25** mm
SAGITTA, h:	**0.40**mm ±0.05 mm
THICKNESS, T_c:	**3.60**mm ±**0.25** mm, center, (**4.0**mm edge)
BEVEL:	**0.3**mm ±0.1mm Face Width at 45° ± 15°
5/ (); ; E, EDGE CHIPS:	**0.2**mm MAX
PERIMETER (OD):	FINE GROUND **400** GRIT OR BETTER
EDGE MARKING:	'^' and '**L1**' laser scribe only as shown.
AR TREATMENT:	SEE NOTE 8 ABOVE

L1 R-50.85



½"Ø

TELAZTEC
PROPRIETARY INFORMATION

DIMENSIONS: mm
TOLERANCE: as noted

Scale **400%**

TelAztec
15 A Street Burlington, MA 01803
D. S. Hobbs
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L1

Plano-Concave Lens
-100mm, UV Fused Silica

Rev	Description	Date
0	-100mm f.l.	17 JUN 2015
4	RAR Performance Spec	08 JAN 2018
5	Laser scribe ID	23 FEB 2021

DWG #
FS-0A-PLCC
-127-040-509

L1